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09/07/174
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Class	Subclass	ISSUE CLASSIFICATION

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PATENT NUMBER

U.S. UTILITY Patent Application

O.I.P.E.	PATENT DATE
SCANNED <i>LM4</i> O.A. <i>204</i>	

APPLICATION NO. 09/874174	CONT/PRIOR	CLASS <i>438</i> <i>451</i>	SUBCLASS <i>41</i>	ART UNIT <i>2812</i> <i>3723</i>	EXAMINER <i>Morgan</i>
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APPLICANTS
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Gerard Moloney
Huey-Ming Wang
Junsheng Yang

TITLE
Chemical mechanical polishing apparatus and method having a retaining ring with a contoured surface

PTO-2040
12/99

ISSUING CLASSIFICATION

ORIGINAL		CROSS REFERENCE(S)						
CLASS	SUBCLASS	CLASS	SUBCLASS (ONE SUBCLASS PER BLOCK)					
INTERNATIONAL CLASSIFICATION								

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<input type="checkbox"/> TERMINAL DISCLAIMER	DRAWINGS			CLAIMS ALLOWED	
	Sheets Drwg.	Figs. Drwg.	Print Fig	Total Claims	Print Claim for O.G.
<input type="checkbox"/> The term of this patent subsequent to _____ (date) has been disclaimed.				NOTICE OF ALLOWANCE MAILED	
<input type="checkbox"/> The term of this patent shall not extend beyond the expiration date of U.S. Patent No. _____					
<input type="checkbox"/> The terminal _____ months of this patent have been disclaimed.				ISSUE FEE	
				ISSUE BATCH NUMBER	

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